

Applicant: Hidetoshi Nishiyama, et al.
e: Method and Its Apparatus for Inspecting Particle
Atty Docket No. 16869S-032100
Sheet 1 of 21

FIG. 1

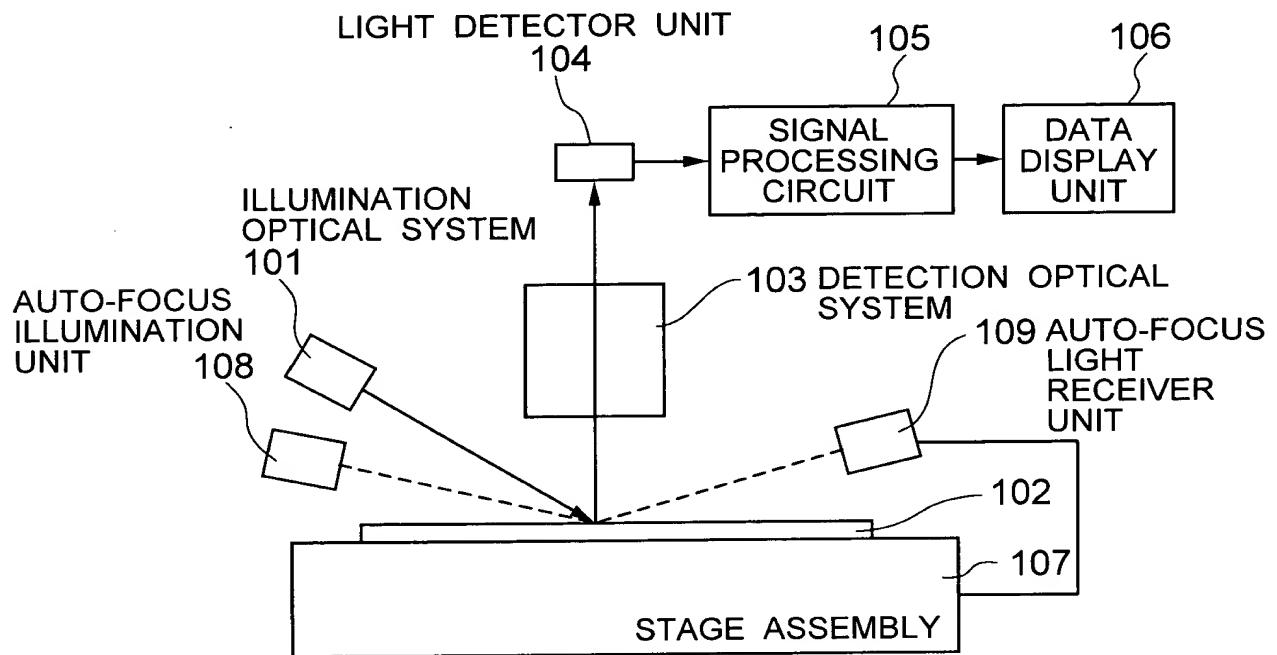


FIG. 2

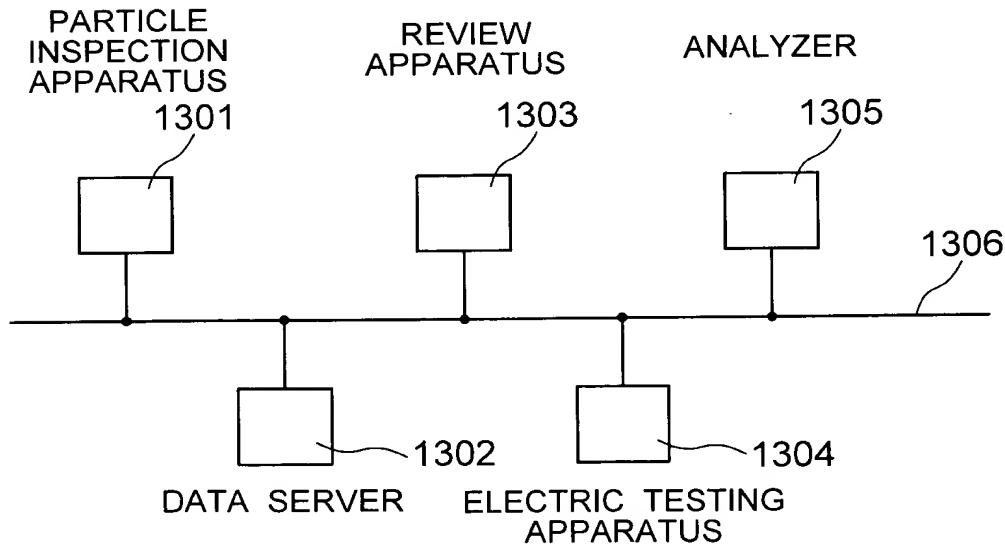


FIG. 3A

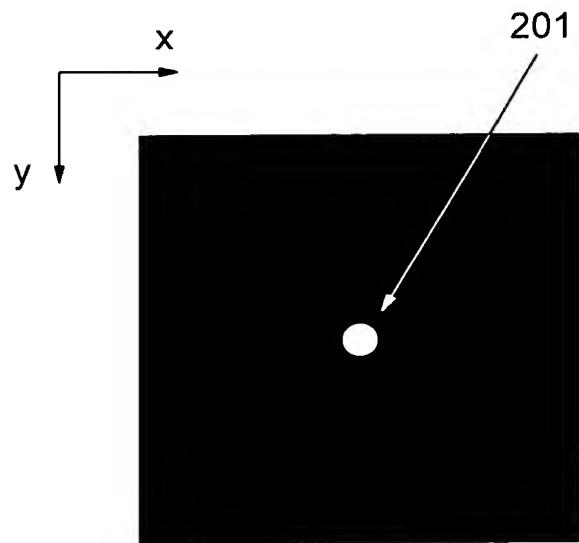


FIG. 3B

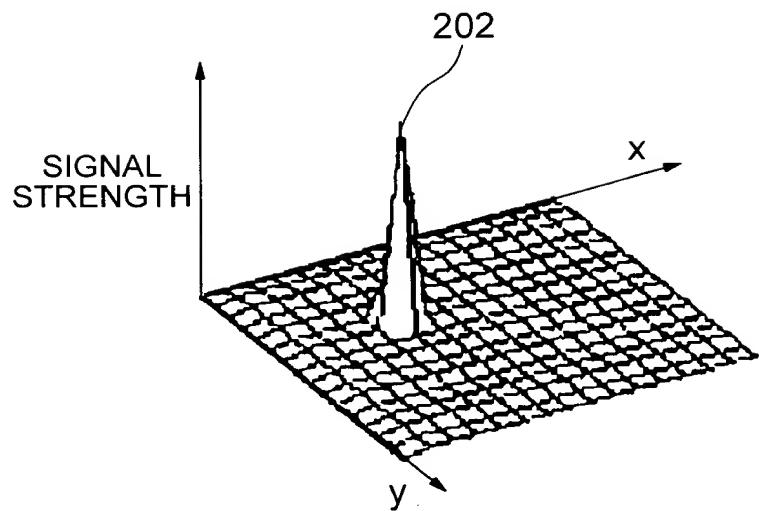


FIG. 4A

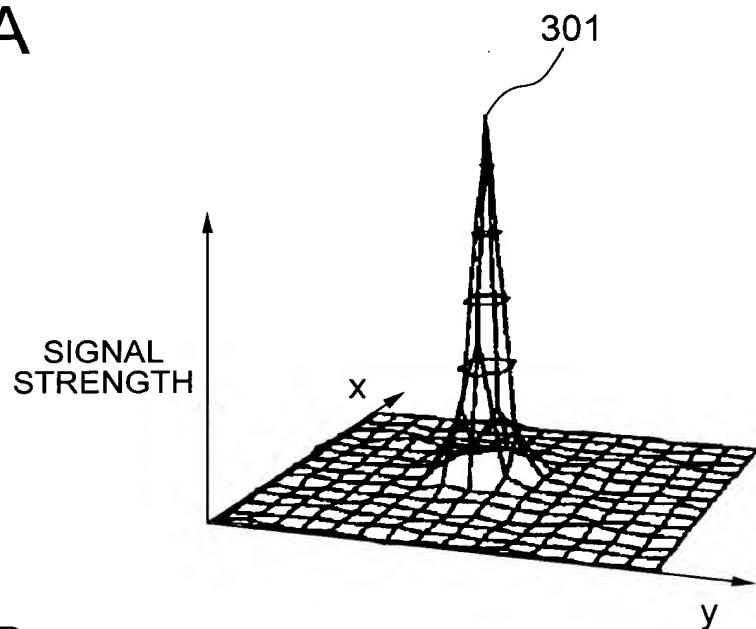


FIG. 4B

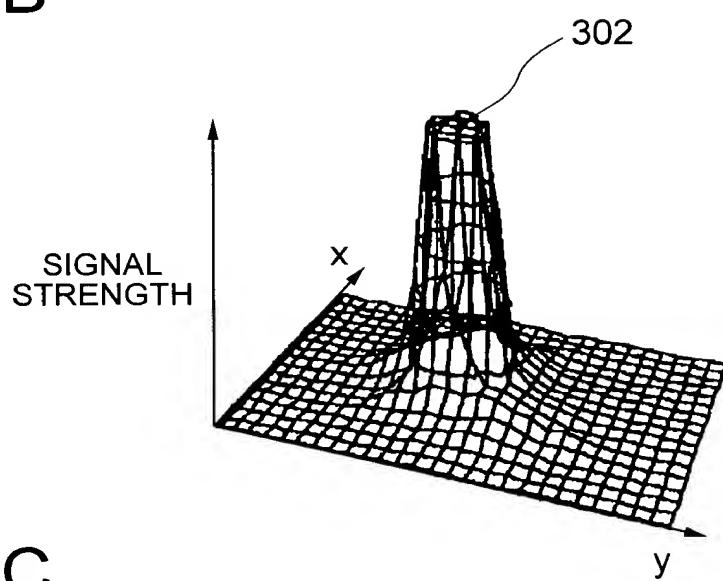


FIG. 4C

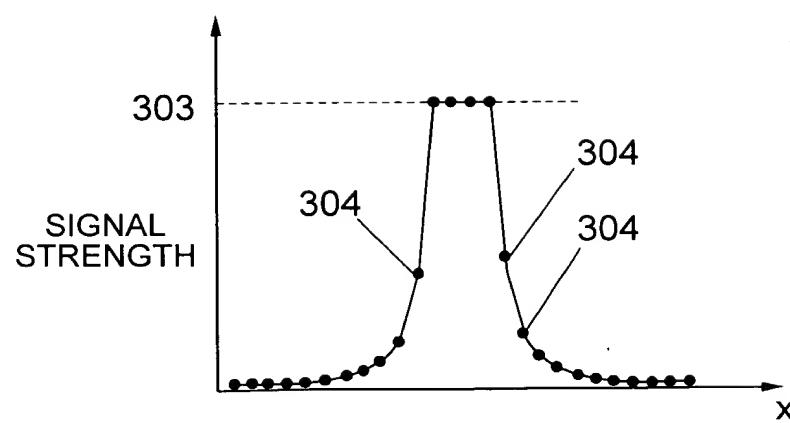


FIG. 5A

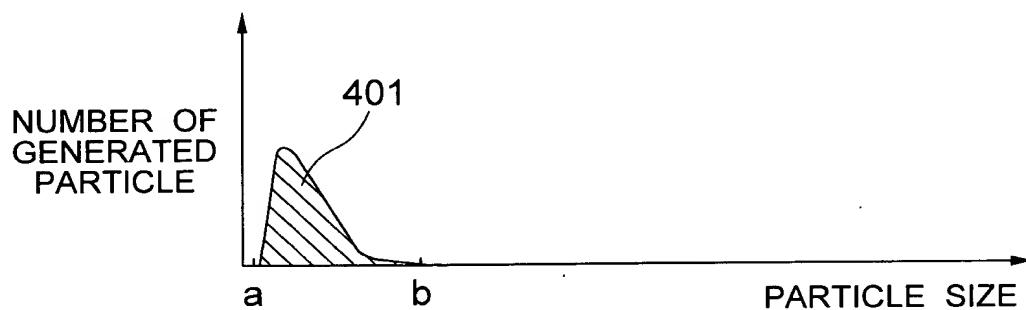


FIG. 5B

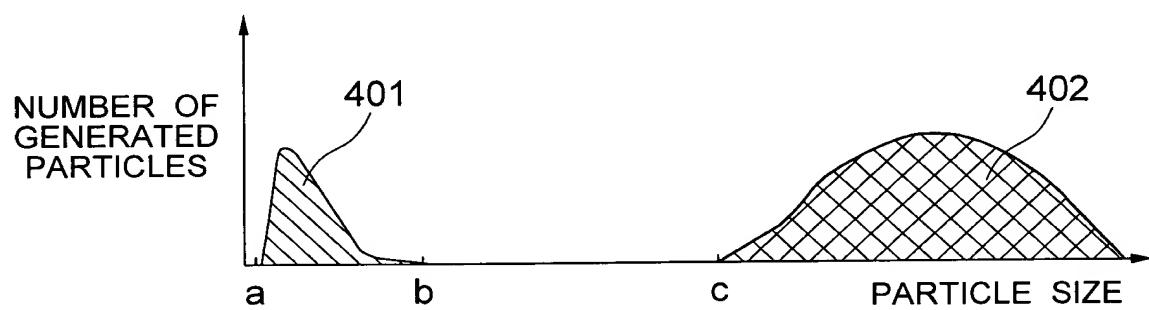


FIG. 5C

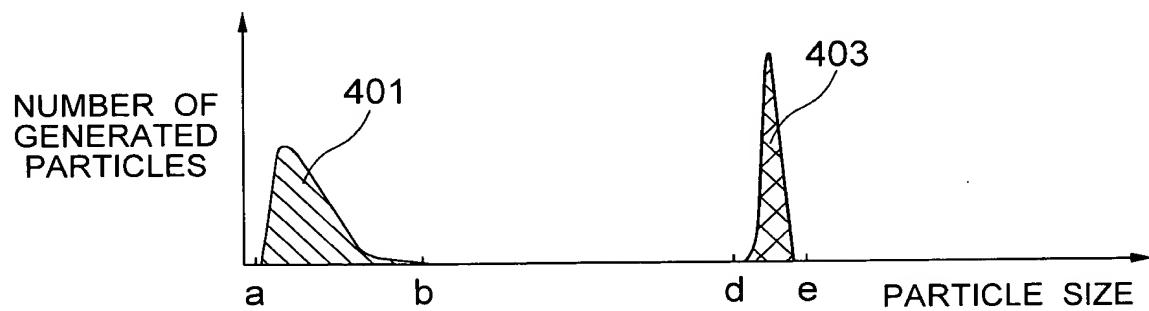


FIG. 6

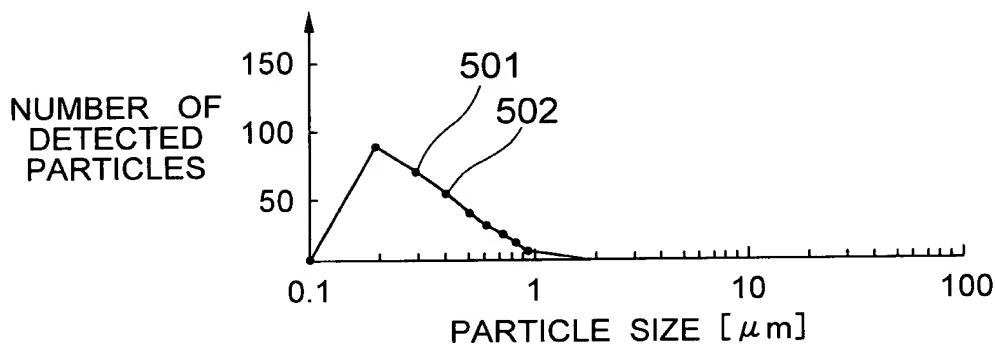


FIG. 7

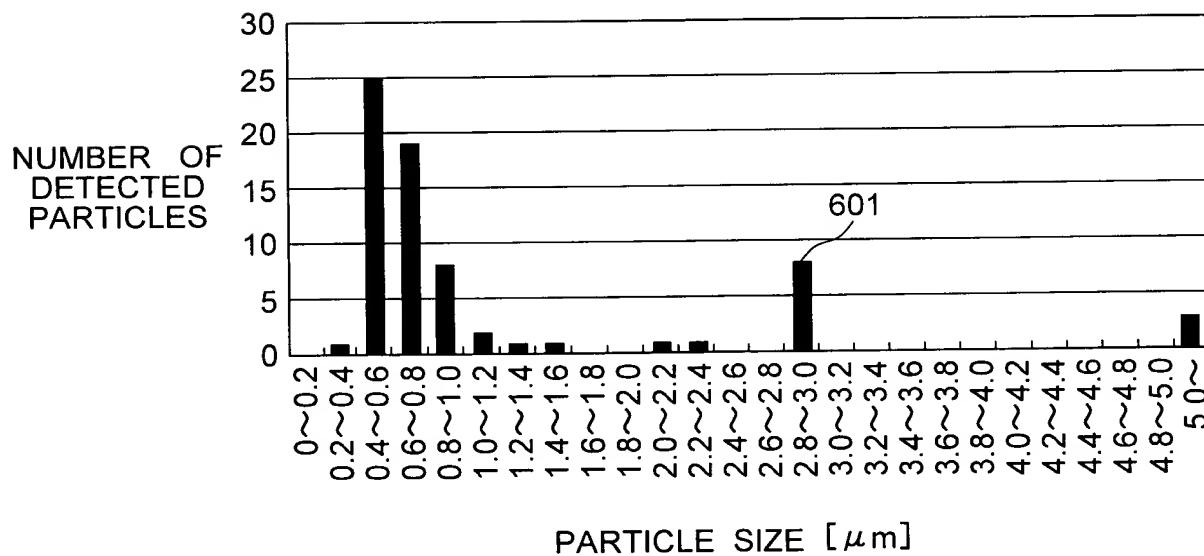


FIG. 8A

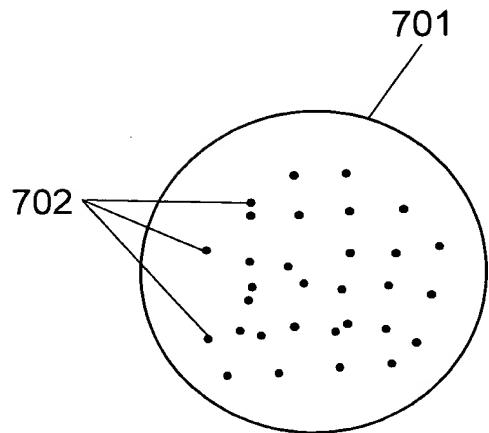


FIG. 8B

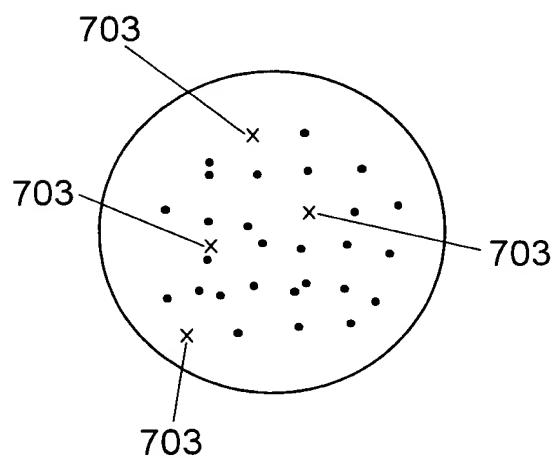


FIG. 9A

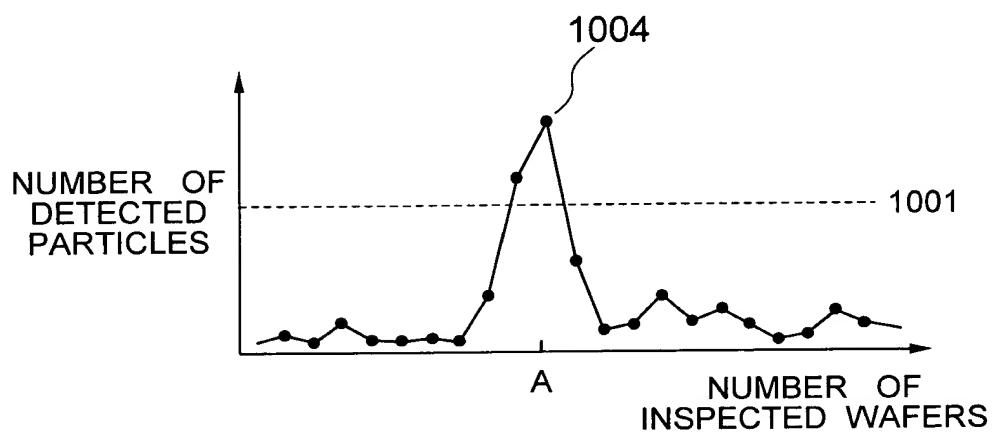


FIG. 9B

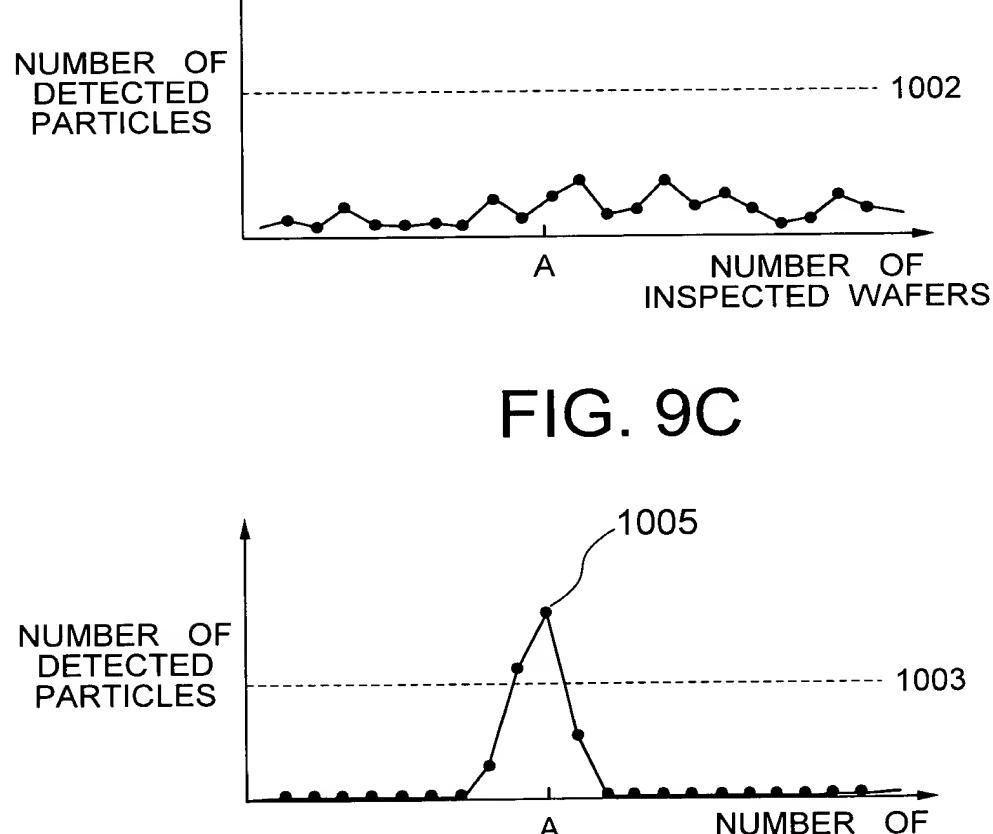


FIG. 10

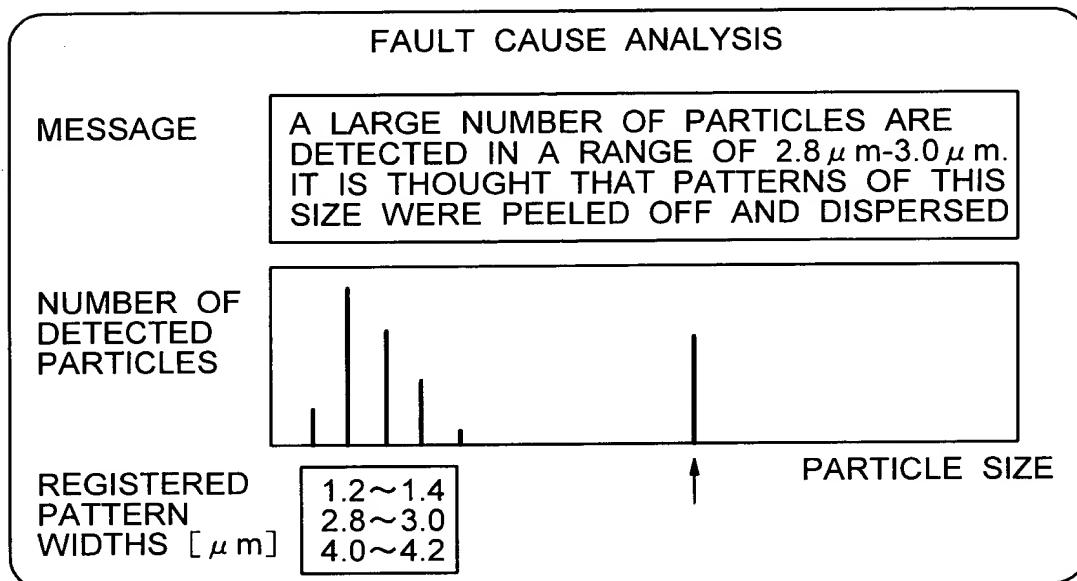


FIG. 11

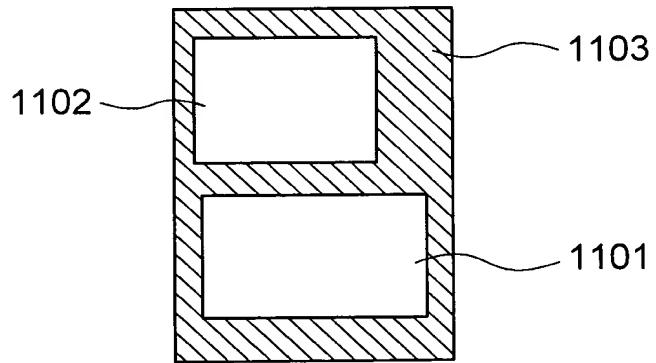


FIG. 12A

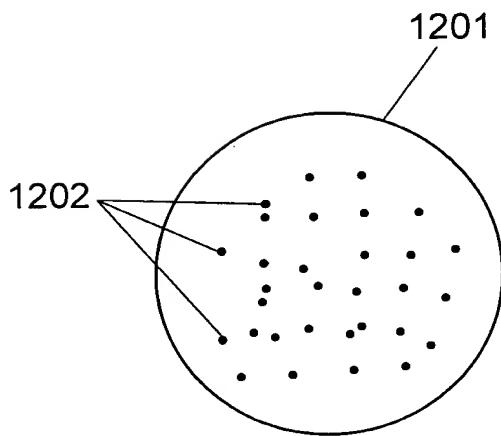


FIG. 12B

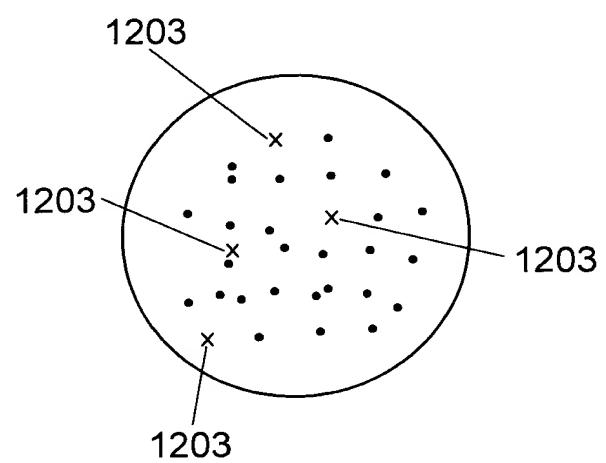


FIG. 13

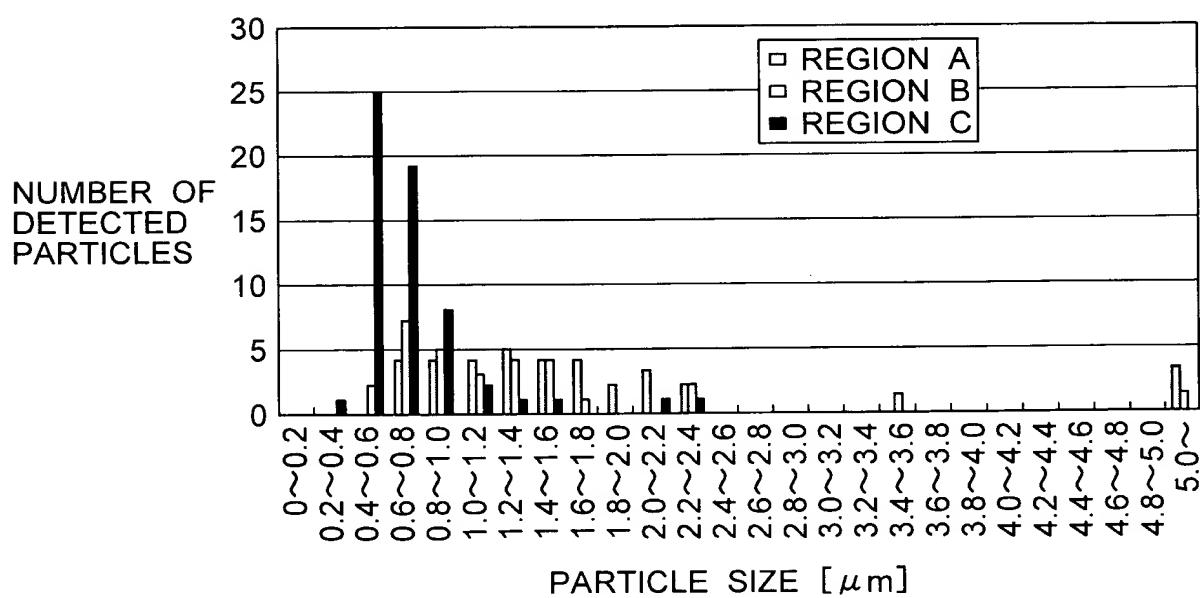


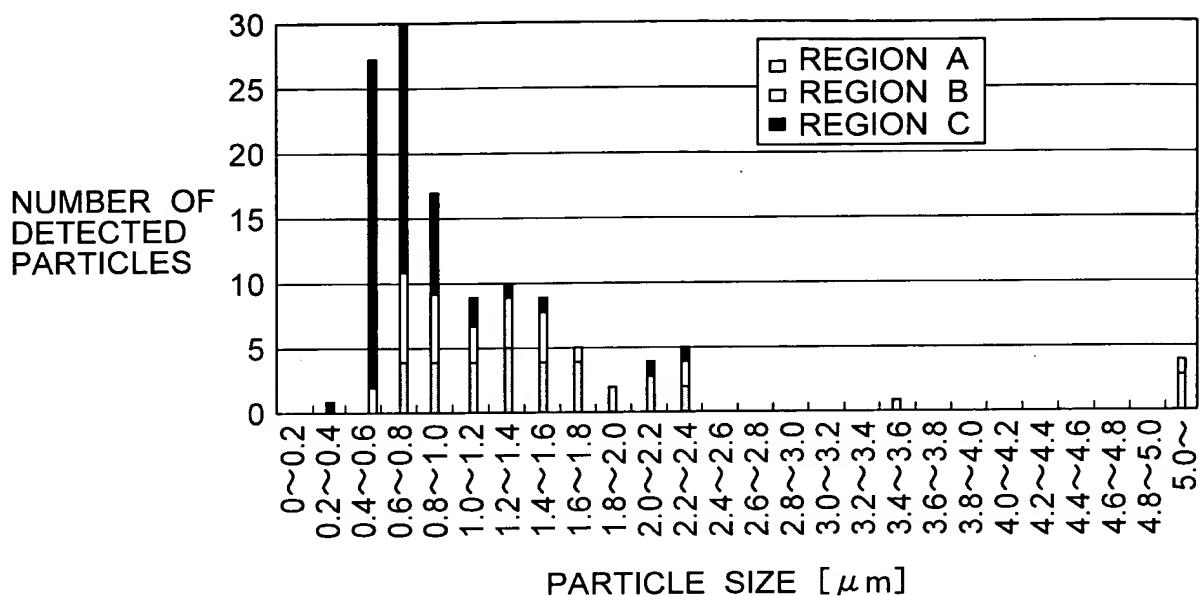
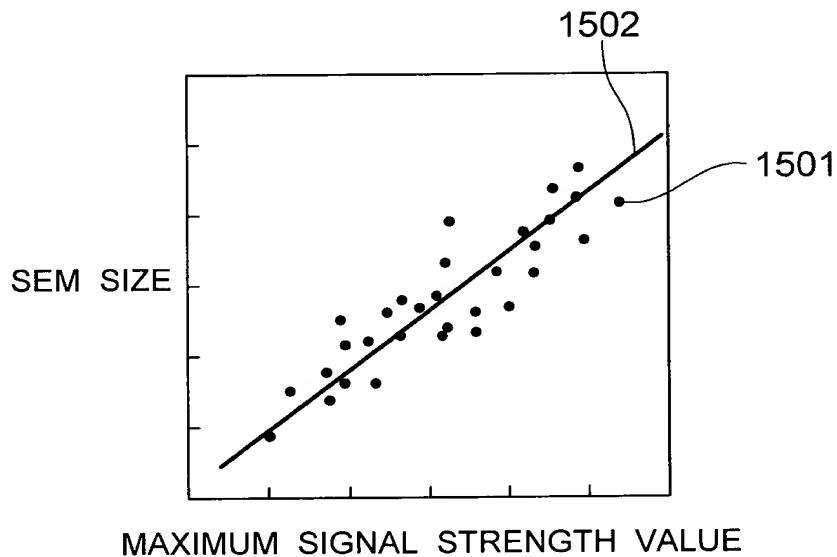
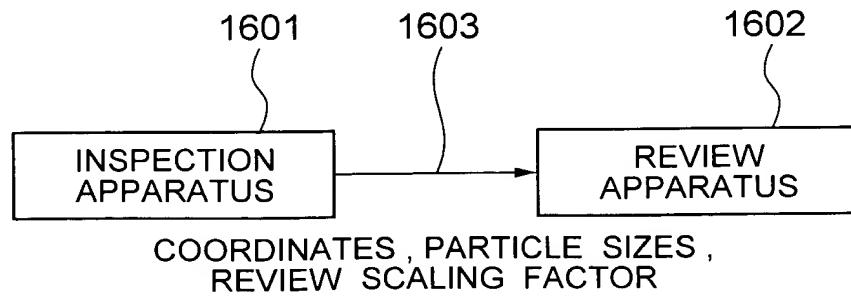
FIG. 14**FIG. 15****FIG. 16**

FIG. 17A

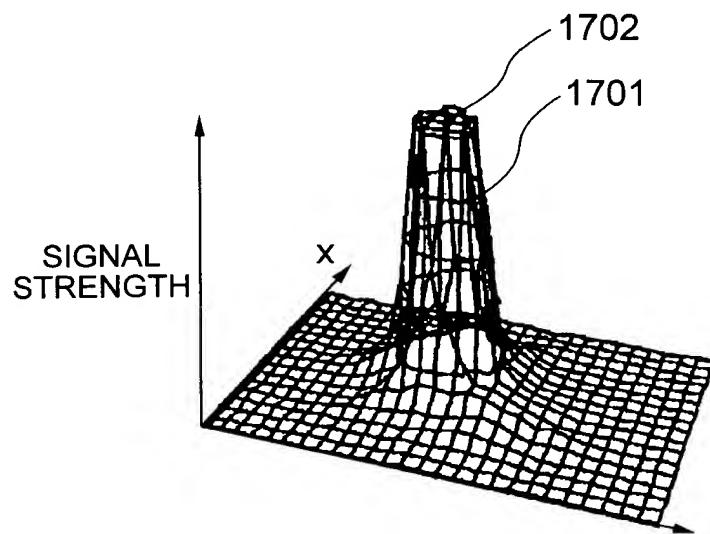


FIG. 17B

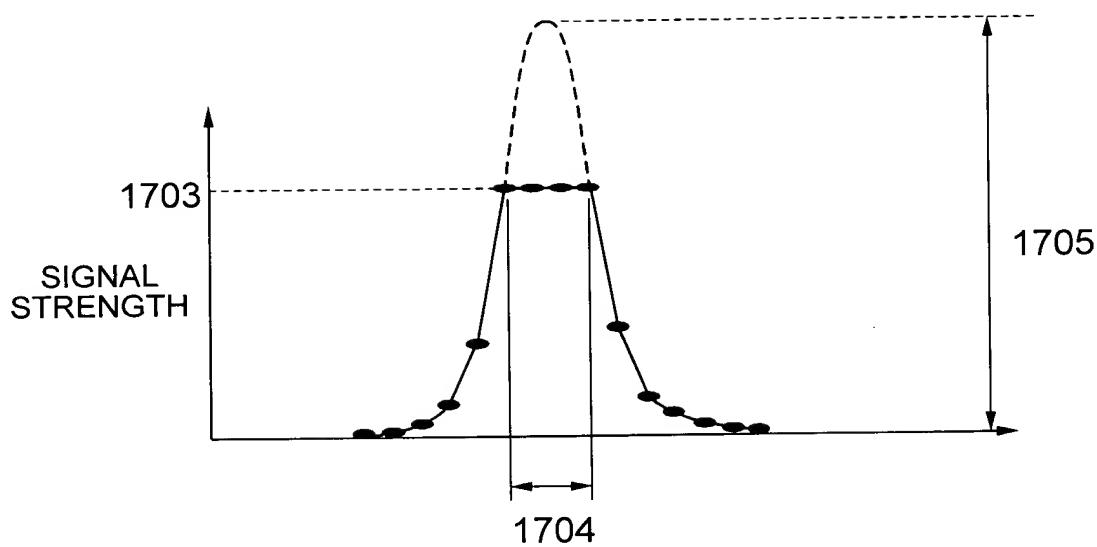


FIG. 17C

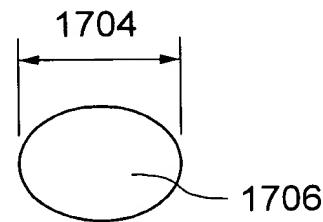
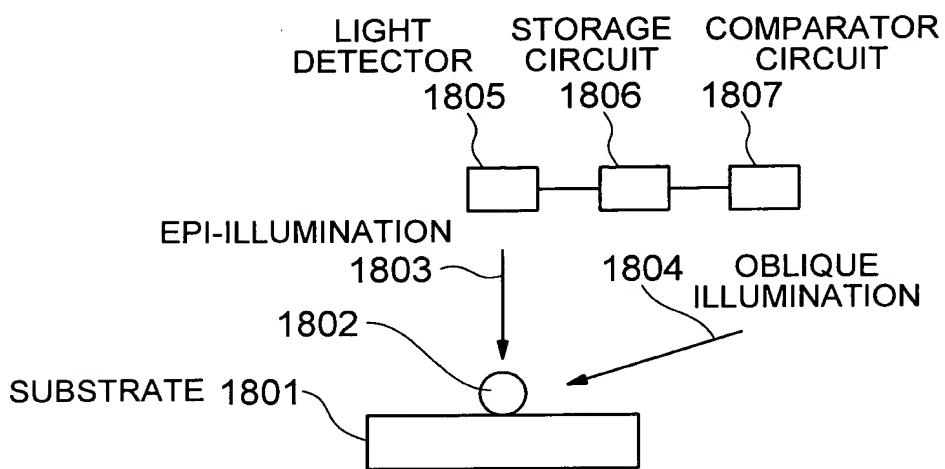


FIG. 18A**FIG. 18B**

	DIFFERENCE IN SCATTERED LIGHT DEPENDING ON ILLUMINATING DIRECTION		SCATTERED LIGHT AMOUNT RATIO (EPI/OBLIQUE)
	EPI-ILLUMINATION	OBLIQUE ILLUMINATION	
PARTICLES	AMOUNT OF SCATTERED LIGHT:LARGE	AMOUNT OF SCATTERED LIGHT:LARGE	SMALL
SCRATCHES	AMOUNT OF SCATTERED LIGHT:LARGE	AMOUNT OF SCATTERED LIGHT:SMALL	LARGE

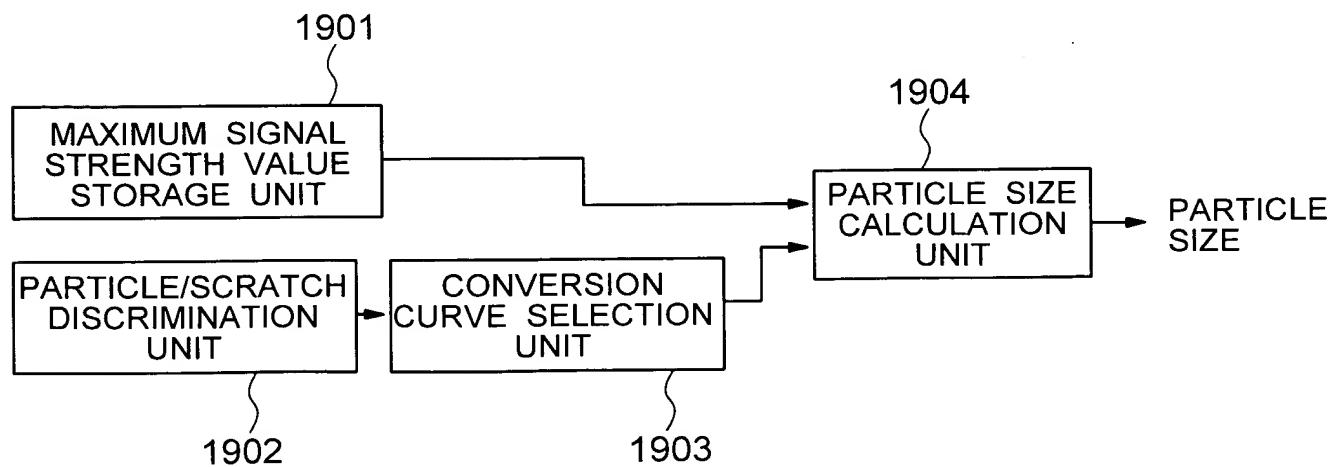
FIG. 19

FIG. 20

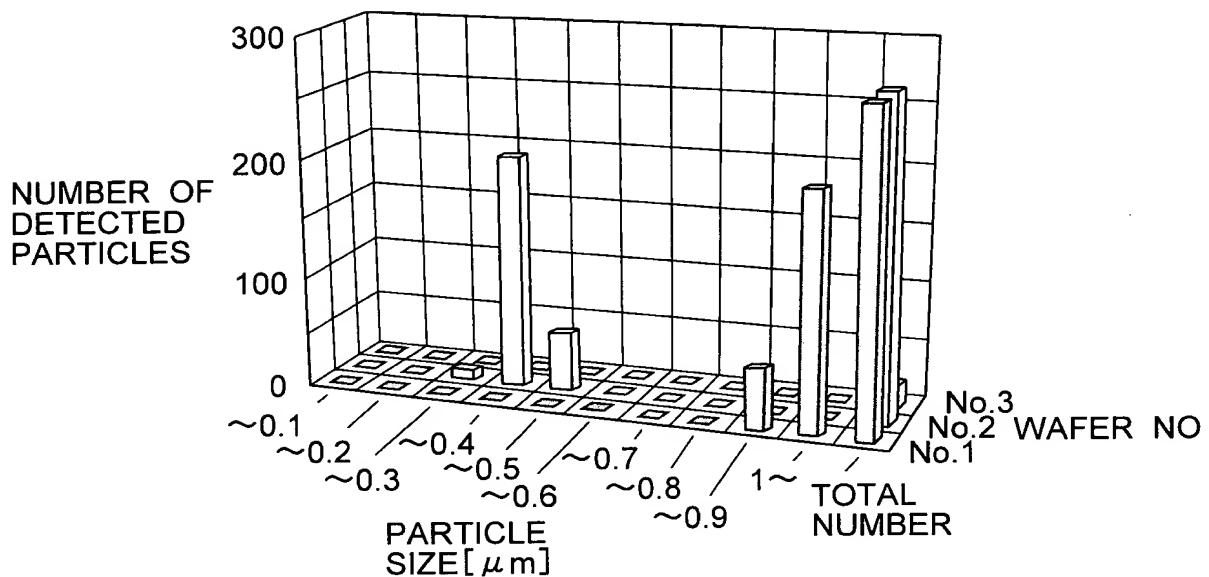


FIG. 21

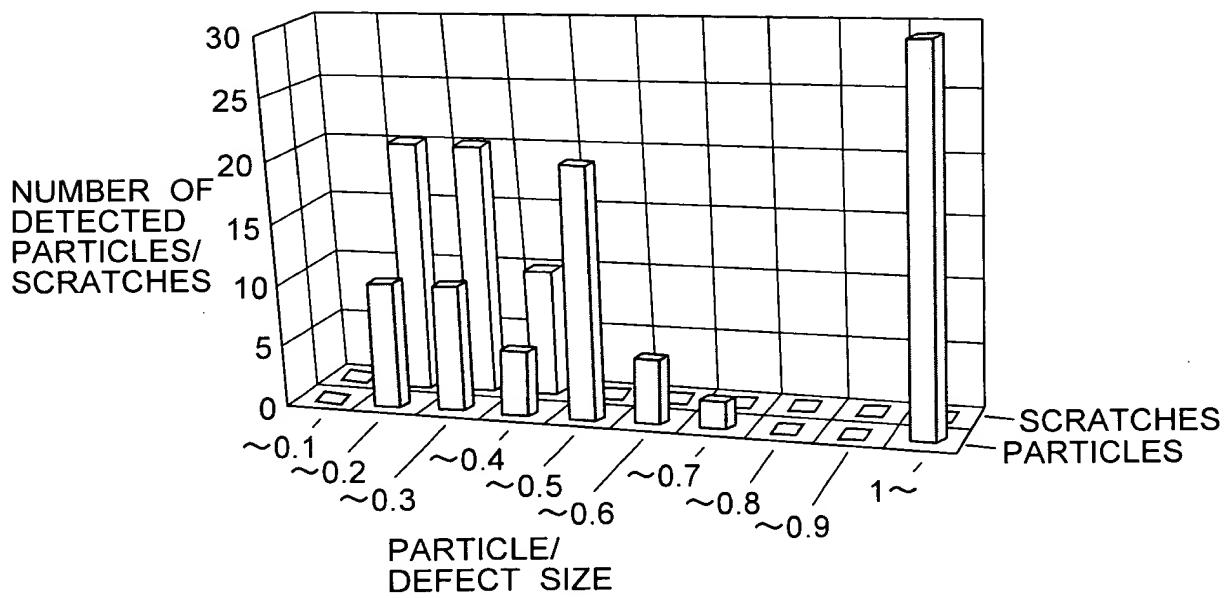


FIG. 22

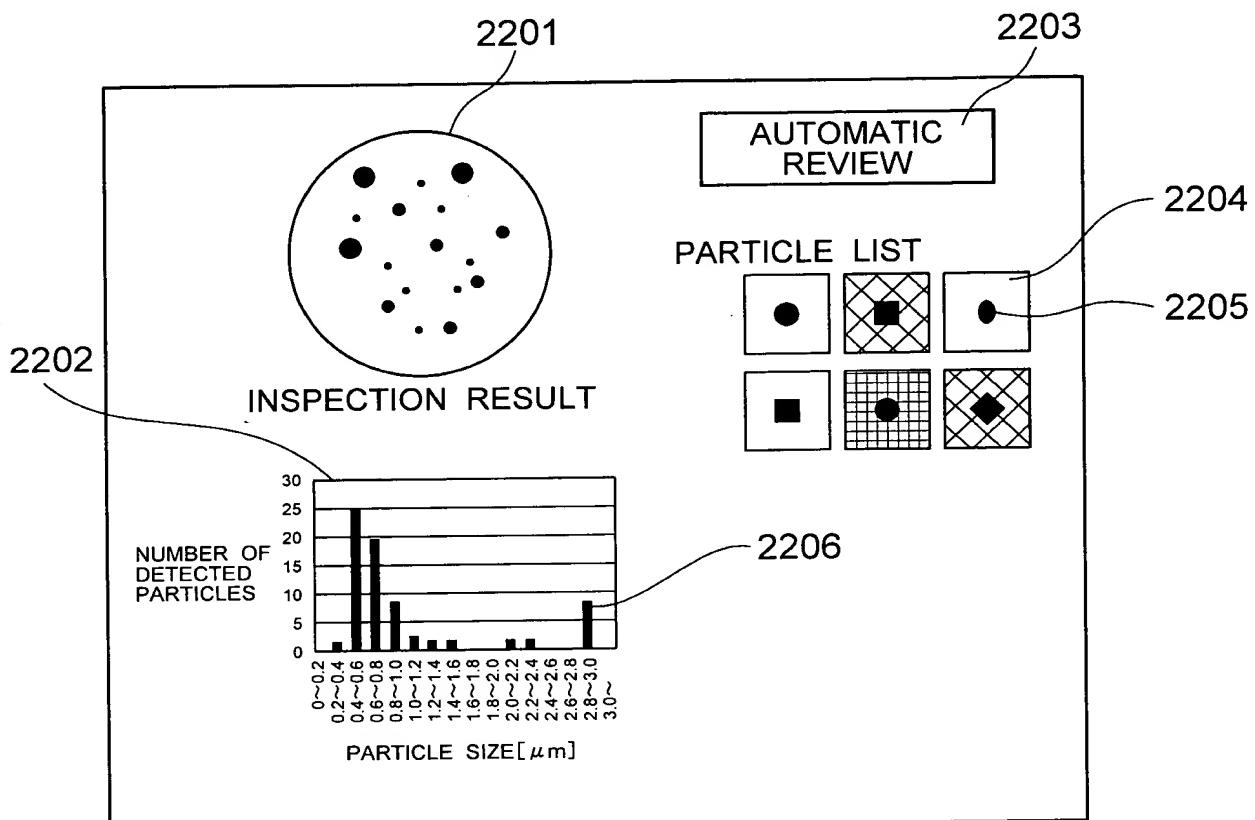


FIG. 23

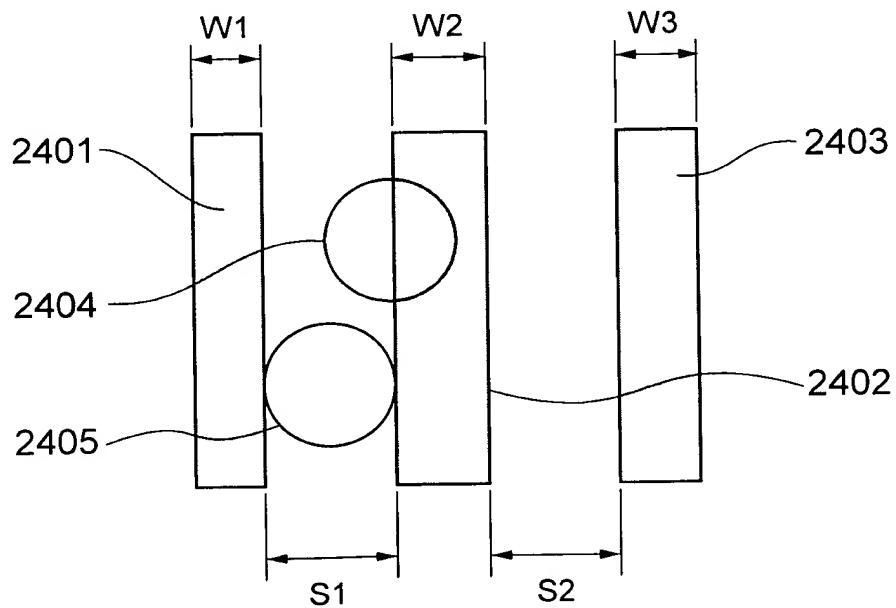


FIG. 24

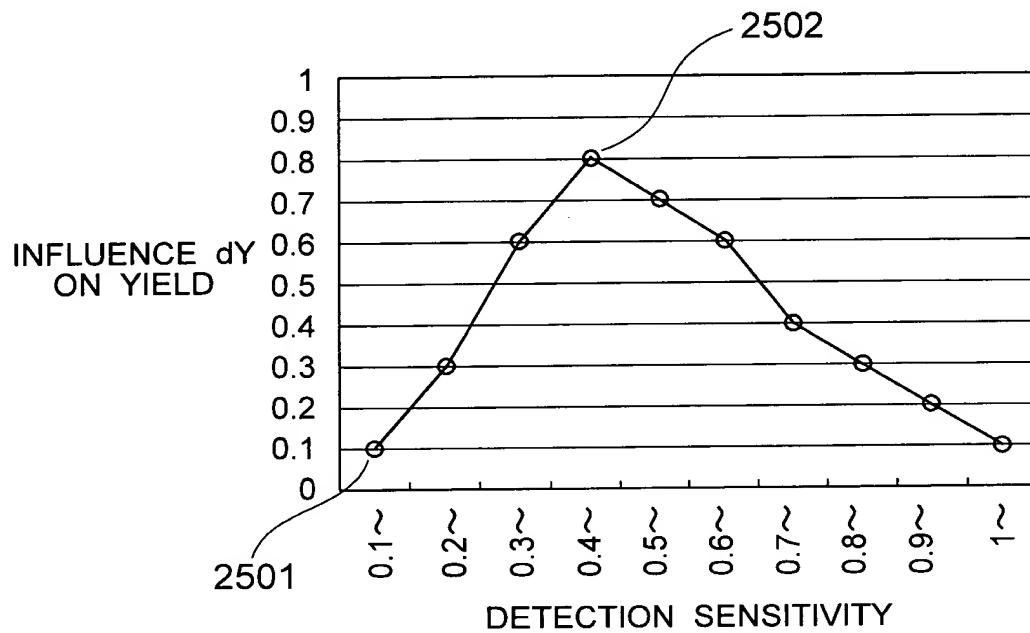


FIG. 25

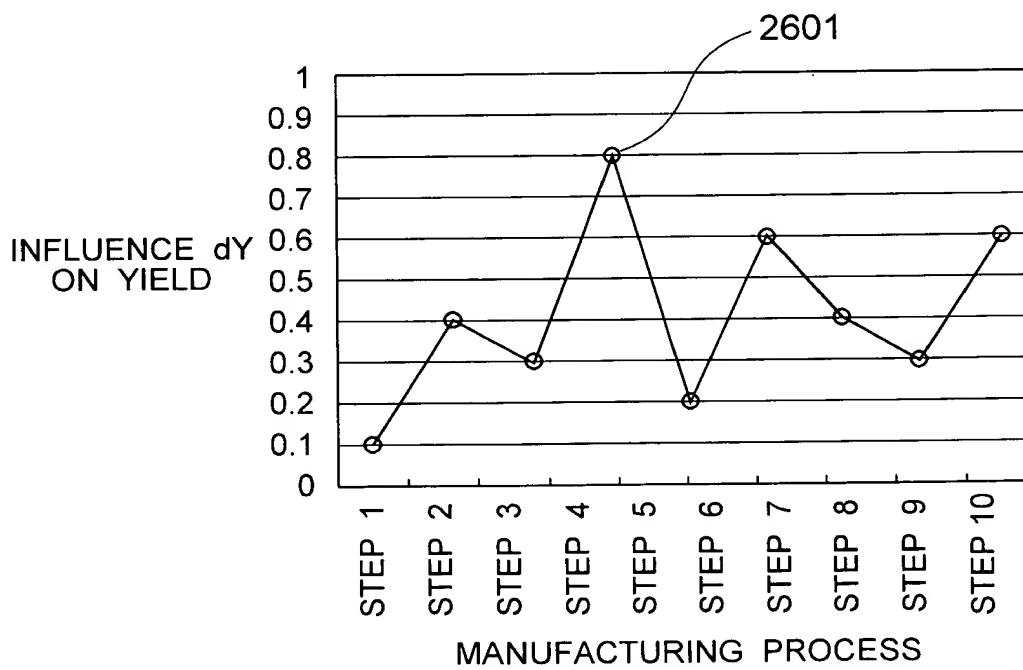


FIG. 26

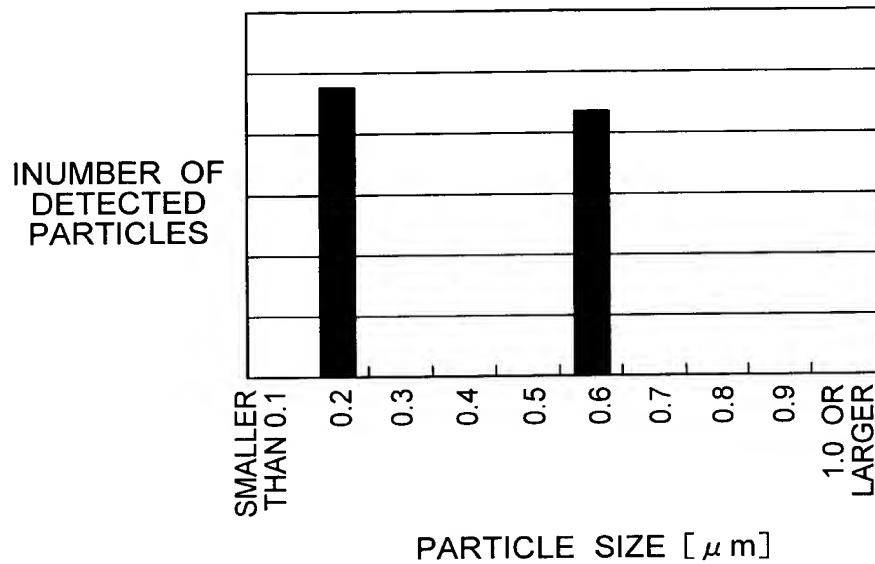


FIG. 27

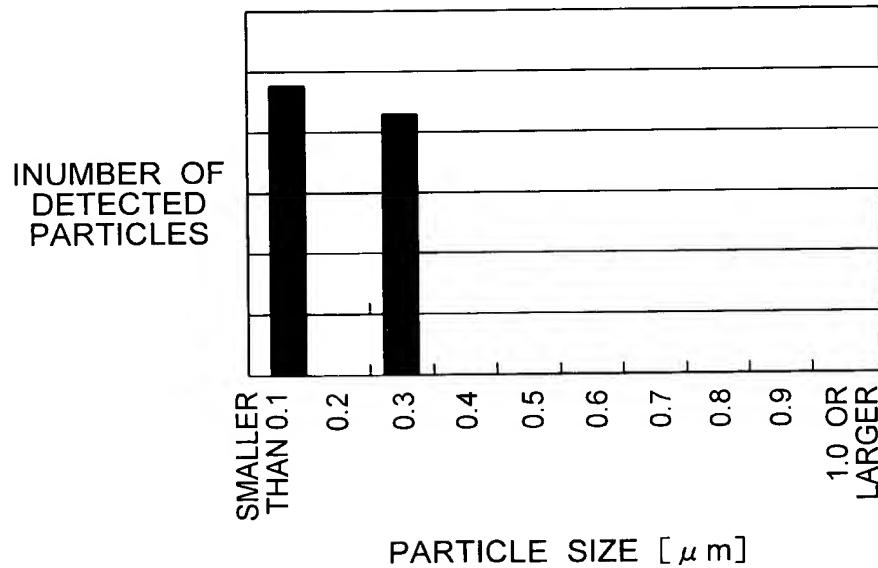


FIG. 28

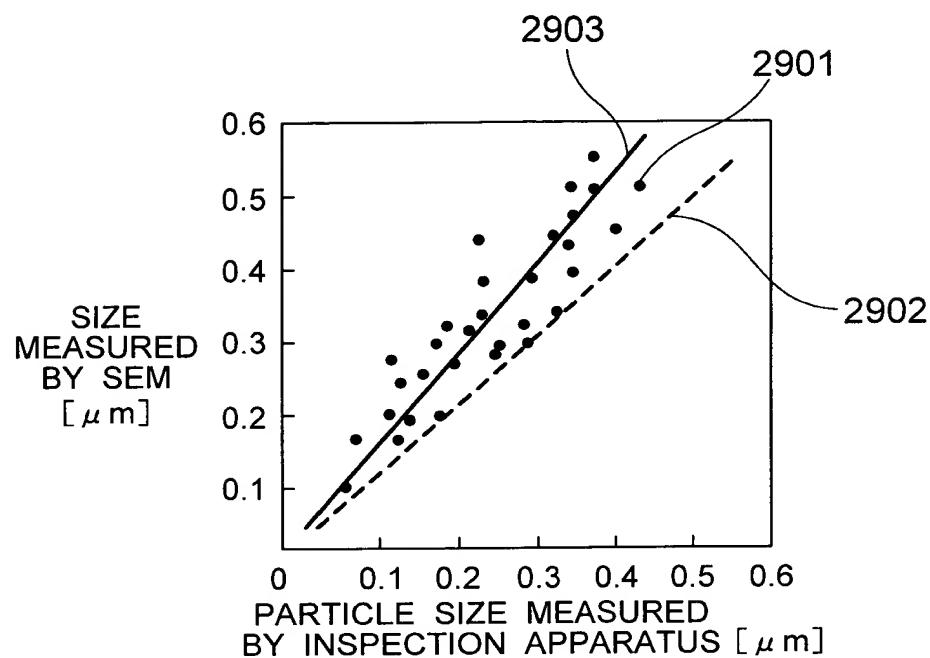


FIG. 29

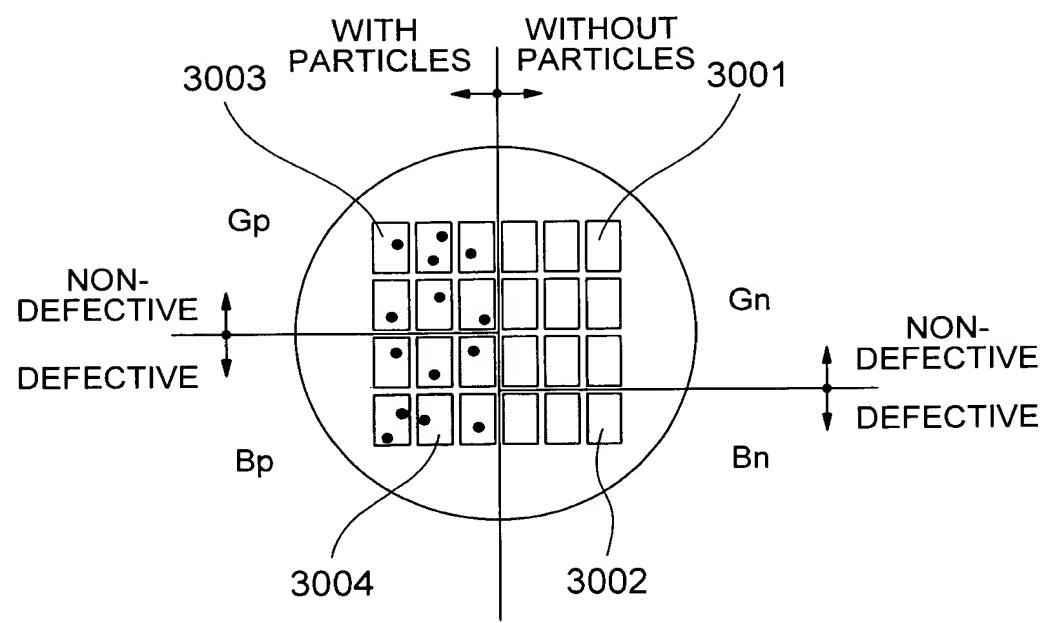


FIG. 30A

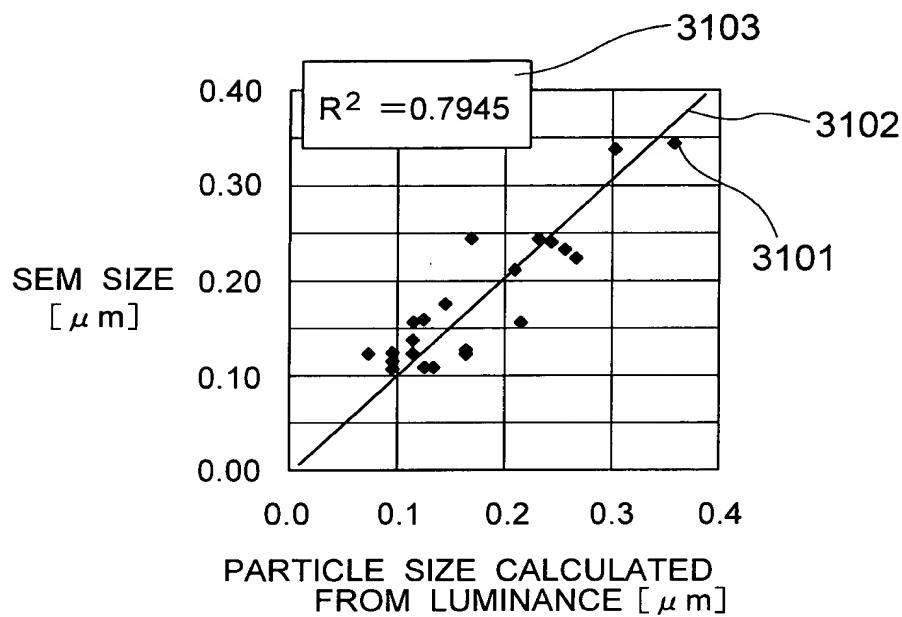


FIG. 30B

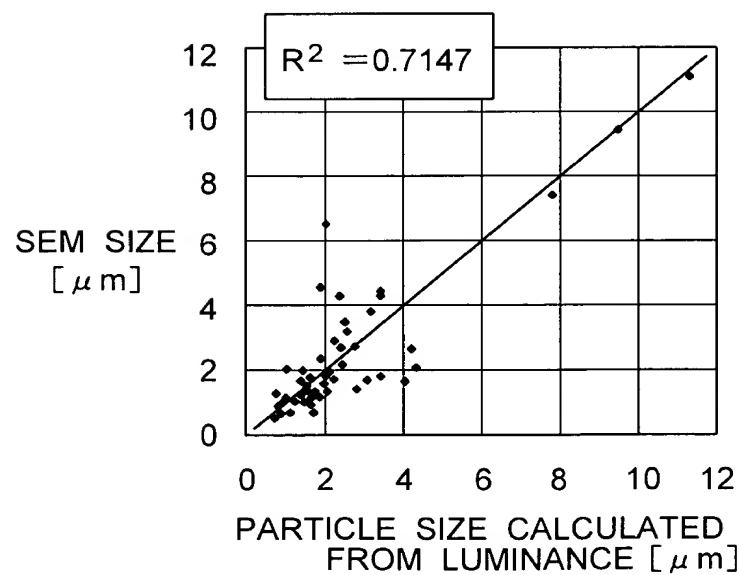


FIG. 31

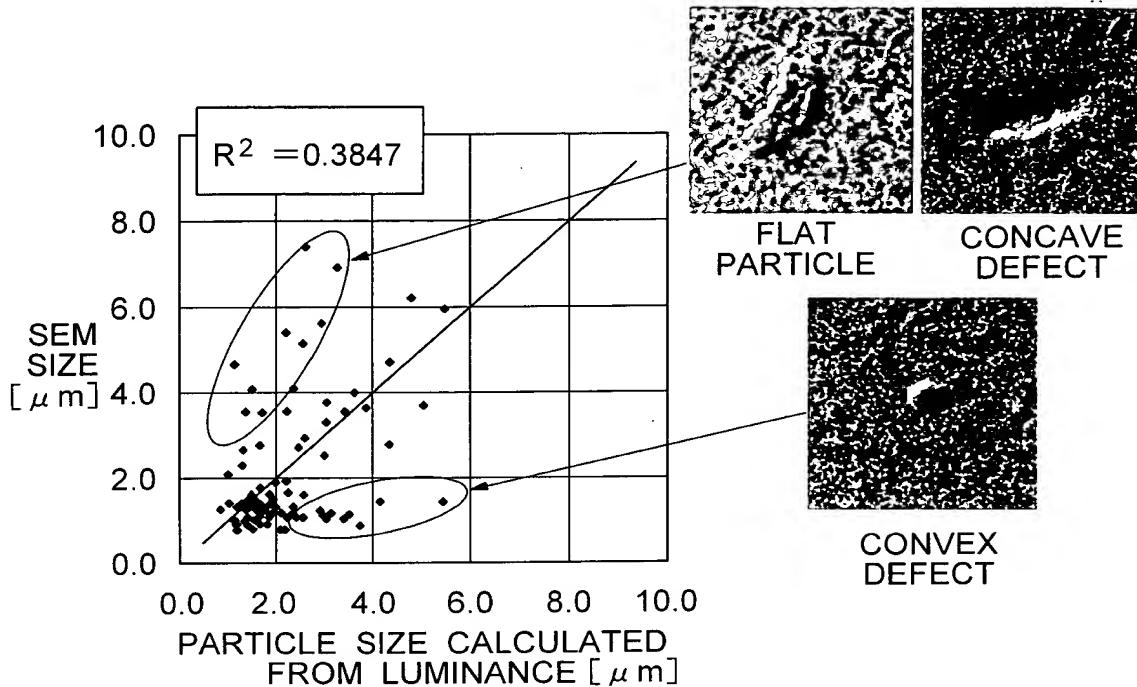


FIG. 32

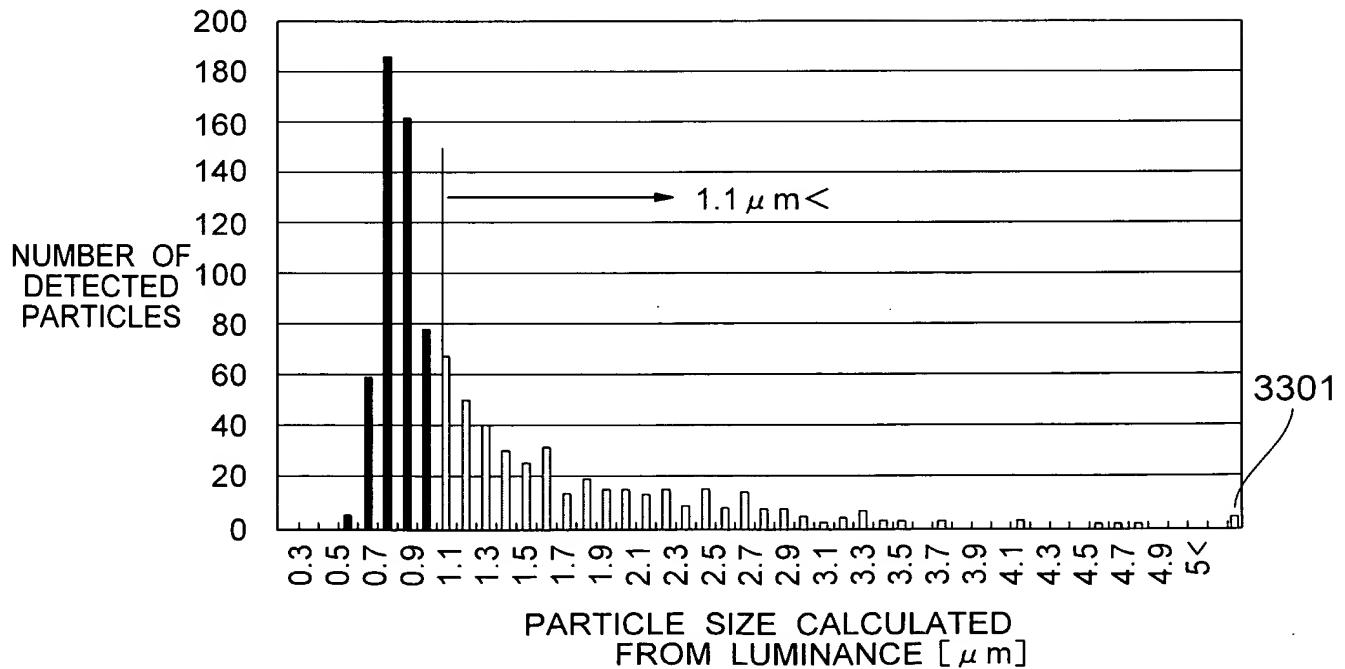


FIG. 33A

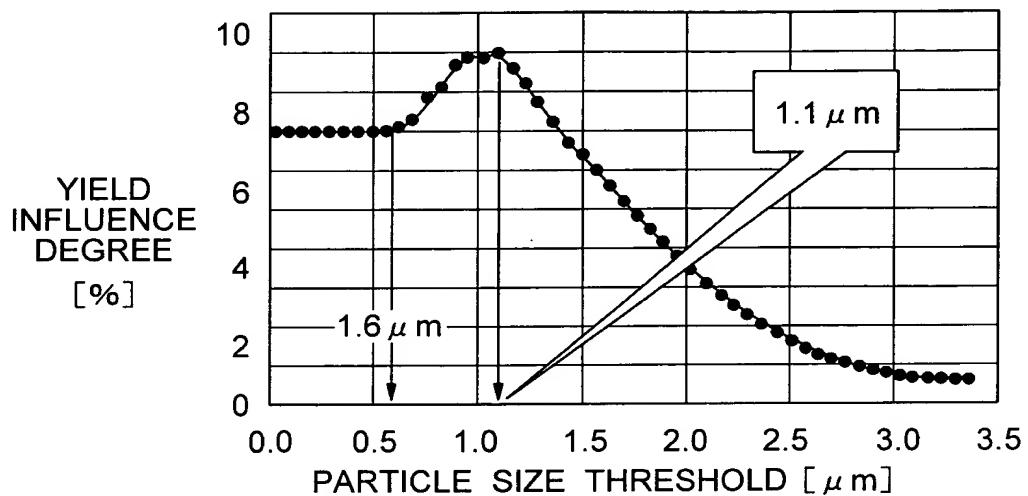


FIG. 33B

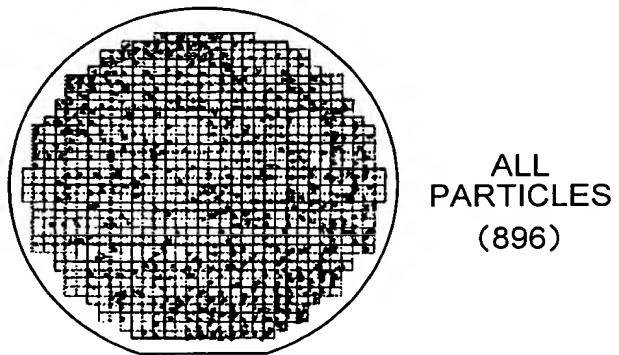
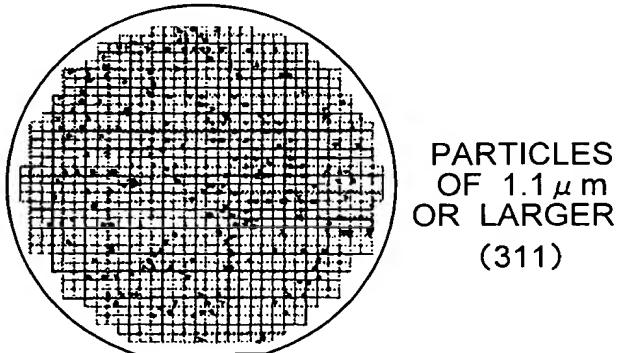


FIG. 33C



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Title: Method and Its Apparatus for Inspecting Particles

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FIG. 34

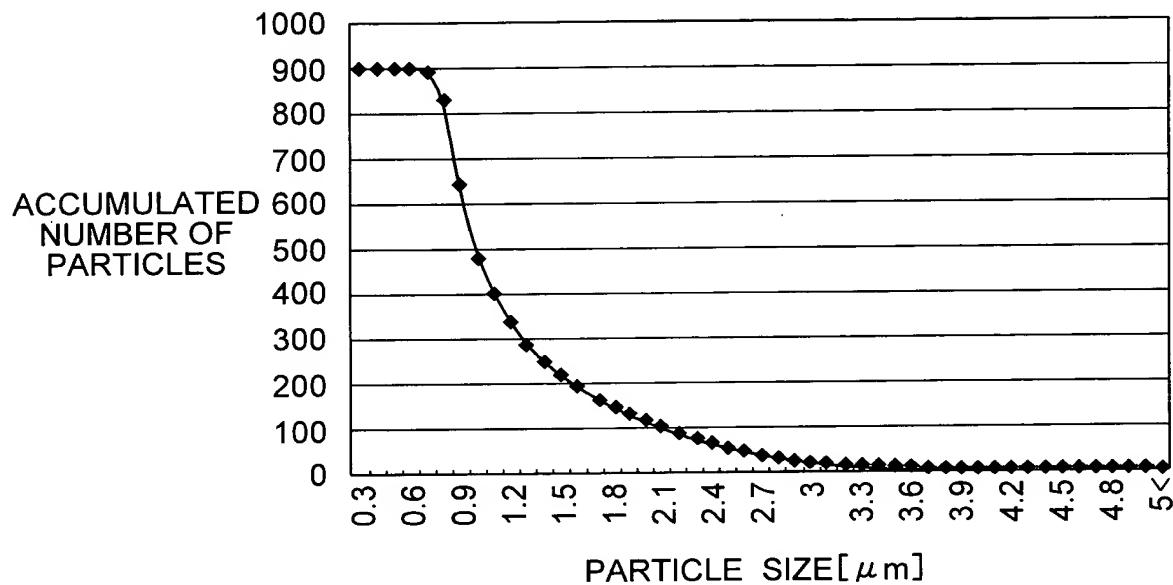


FIG. 35

